# REQUEST FOR CORRECTION OF APPARENT ERROR

Commissioner, Patent Office Esq.

1. Indication of International Application
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4. Object of correction
   (1) Page 8 of the specification

5. Content of correction Recited in attached sheet
   (1) Correct the description "[Fig. 13] (a) is a perspective view showing the configuration of an electromechanical signal selection device according to Embodiment 5 of the present invention." as "[Fig. 13] A perspective view showing the configuration of an electromechanical signal selection device according to Embodiment 5 of the present invention."

6. List of Attached Documents
   New sheet of page 8 of the specification

micro-vibrator; and (b) is a diagram showing a vibrating state of the micro-vibrator.

[Fig. 11] (a) is a perspective view showing the configuration of an electromechanical signal selection device according to Embodiment 3 of the present invention, and (b) is a perspective view showing a modification of the electromechanical signal selection device in Fig. 11(a).

[Fig. 12] (a) is a perspective view showing the configuration of an electromechanical signal selection device according to Embodiment 4 of the present invention, and (b) is a perspective view showing the configuration of an electromechanical signal selection device according to a modification of Embodiment 4 of the present invention.

[Fig. 13] A perspective view showing the configuration of an electromechanical signal selection device according to Embodiment 5 of the present invention.

[Fig. 14] (a) is a perspective view showing the structure of a micro-vibrator according to Embodiment 6 of the present invention, and (b) is a perspective view showing the structure of a micro-vibrator according to a modification of Embodiment 6 of the present invention.

[Fig. 15] Graphs showing signal selection characteristics according to Embodiment 7 of the present invention: in which (a) is a graph showing the case where the material of a micro-vibrator 101 shows a linear or nonlinear change in electric